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### **DIELECTRIC PROTECTION LAYER IN MIDDLE-OF-LINE INTERCONNECT STRUCTURE MANUFACTURING METHOD**

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#### **Abstract**

In some embodiments, the present disclosure relates to an integrated chip include a gate structure over a substrate. A pair of source/drain structures is on opposing sides of the gate structure. A dielectric layer is over the substrate and around the gate structure. The dielectric layer comprises a first material. An etch stop layer is adjacent to opposing sidewalls of the gate structure. A capping layer is on the gate structure. The capping layer includes a first segment and a second segment under the first segment. The first segment contacts the etch stop layer and the second segment contacts the gate structure. The capping layer comprises a second material different from the first material. A conductive structure is over a first source/drain structure in the pair of source/drain structures. The conductive structure contacts the capping layer and the etch stop layer.

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## **Background/Summary**

REFERENCE TO RELATED APPLICATIONS [0001] This Application is a Continuation of U.S. application Ser. No. 18/423,648, filed on Jan. 26, 2024, which is a Divisional of U.S. application Ser. No. 17/459,065, filed on Aug. 27, 2021 (now U.S. Pat. No. 11,942,372, issued on Mar. 26, 2024). The contents of the above-referenced Patent Applications are hereby incorporated by reference in their entirety.

### **BACKGROUND**

[0002] In the manufacturing of integrated circuits (ICs), devices are formed on a wafer and connected by conductive interconnect layers. These conductive interconnect layers can be formed during so-called middle-of-the-line (MOL) processes or back-end-of-line (BEOL) processes. MOL and BEOL processes are similar in that they both form openings in a dielectric layer (e.g. contact holes, trenches, or via holes in a dielectric layer), and then fill these openings with a conductive material. MOL differs from BEOL in that the MOL typically occurs earlier in the fabrication process, and may refer to the process of forming contacts directly on or close to device structures such as a gate electrode or a source/drain region; whereas BEOL typically occurs later in the fabrication process, and may refer to the process of forming successive metallization layers and vias above the contacts formed by MOL.

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## **Description**

### **BRIEF DESCRIPTION OF THE DRAWINGS**

[0003] Aspects of the present disclosure are best understood from the following detailed description when read with the accompanying figures. It is noted that, in accordance with the standard practice in the industry, various features are not drawn to scale. In fact, the dimensions of the various features may be arbitrarily increased or reduced for clarity of discussion.

[0004] FIG. 1 illustrates a cross-sectional view of some embodiments of an integrated chip having a gate capping layer over a gate electrode.

[0005] FIGS. 2A-2C and 3A-3B illustrate various cross-sectional views of some additional embodiments of an integrated chip having a gate capping layer over a gate electrode.

[0006] FIG. 4 illustrates a perspective view of some embodiments of an integrated chip having a gate capping layer over a gate electrode.

[0007] FIGS. 5-14 illustrate various cross-sectional views of some embodiments of a method of forming an integrated chip having a gate capping layer over a gate electrode.

[0008] FIGS. 15-17 illustrate various cross-sectional views of some embodiments of a second method of forming an integrated chip having a gate capping layer over a gate electrode.

[0009] FIGS. 18-22B illustrate various cross-sectional views of some additional alternative embodiments of the second method.

[0010] FIG. 23 illustrates a flow diagram of some embodiments of a method of forming an

integrated chip having a gate capping layer over a gate electrode.

## DETAILED DESCRIPTION

[0011] The following disclosure provides many different embodiments, or examples, for implementing different features of the provided subject matter. Specific examples of components and arrangements are described below to simplify the present disclosure. These are, of course, merely examples and are not intended to be limiting. For example, the formation of a first feature over or on a second feature in the description that follows may include embodiments in which the first and second features are formed in direct contact, and may also include embodiments in which additional features may be formed between the first and second features, such that the first and second features may not be in direct contact. In addition, the present disclosure may repeat reference numerals and/or letters in the various examples. This repetition is for the purpose of simplicity and clarity and does not in itself dictate a relationship between the various embodiments and/or configurations discussed.

[0012] Further, spatially relative terms, such as “beneath,” “below,” “lower,” “above,” “upper” and the like, may be used herein for ease of description to describe one element or feature's relationship to another element(s) or feature(s) as illustrated in the figures. The spatially relative terms are intended to encompass different orientations of the device in use or operation in addition to the orientation depicted in the figures. The apparatus may be otherwise oriented (rotated 90 degrees or at other orientations) and the spatially relative descriptors used herein may likewise be interpreted accordingly.

[0013] Integrated chips may include a number of semiconductor devices (e.g., transistors) disposed over and/or within a substrate. A middle-of-the-line (MOL) interconnect structure may be disposed over the substrate. The MOL interconnect structure includes conductive contacts, interconnect vias, and metal lines that play a significant role in semiconductor device and circuit performance. The integrated chip comprises a transistor structure disposed over a substrate and including a pair of source/drain regions disposed on the substrate and a gate electrode between the pair of source/drain regions. A lower inter-level dielectric (ILD) layer is disposed over the pair of source/drain regions and surrounding the gate electrode. The gate electrode may be recessed from a top surface of the lower ILD layer. Further, a gate capping layer may be disposed on the gate electrode. By recessing the gate electrode and implementing the gate capping layer, the gate electrode is isolated and protected from neighboring conductive features, and thus leakage issues can be reduced or eliminated. In addition, the MOL interconnect structure comprises conductive contacts overlying the pair of source/drain regions and disposed on opposing sides of the gate electrode. As scaling of device features continues, distance between various conductive contacts and interconnect features shrink, and current leakage with parasitic capacitance become key limiting factors for device performance. It is desired to reduce or prevent current leakage among contacts and other conductive features while at the same time limiting resistance and capacitance increase.

[0014] One challenge with the above integrated chip is fabrication of the conductive contacts without degrading device performance and/or endurance. For example, during fabrication of the MOL interconnect structure an etching process is performed on the lower ILD layer to form conductive contact openings within the lower ILD layer and expose an upper surface of the source/drain regions. A conductive material is formed over the source/drain regions and within the conductive contact openings. Further, a planarization process is performed on the conductive material until an upper surface of the gate capping layer is reached, thereby forming a plurality of lower source/drain contacts. However, the etching process may include exposing the lower ILD layer and the gate capping layer to one or more fluorine-based etchants. The one or more fluorine-based etchants may remove portions of the gate capping layer, thereby reducing a thickness of the gate capping layer and/or rounding the corners of the gate capping layer. This may result in the formation of volatile by-products (e.g., silicon tetrafluoride) on the gate capping layer and/or may degrade interfaces between the gate capping layer, thereby reducing a structural integrity and/or an

endurance of the integrated chip. In addition, the rounded corners of the gate capping layer may result in a reduced distance between adjacent contacts, thereby increasing parasitic capacitance and/or leakage current within the MOL interconnect structure. This, in part, may degrade a performance of the integrated chip.

[0015] Accordingly, the present disclosure relates to an integrated chip with an improved MOL interconnect structure and associated manufacturing methods to improve parasitic capacitance and increase structural integrity. As a result, device reliability and performance are improved. The integrated chip comprises a transistor structure disposed over a substrate and including a pair of source/drain regions disposed on the substrate and a gate electrode between the source/drain regions. A lower inter-level dielectric (ILD) layer is disposed over the pair of source/drain regions and surrounding the gate electrode. A gate capping layer is disposed on the gate electrode. Further, source/drain contacts are disposed over the pair of source/drain regions and on opposing sidewalls of the gate electrode. During fabrication of the source/drain contacts, a selective etch and deposition process may be performed on the lower ILD layer and the gate capping layer to form contact openings within the lower ILD layer and over the source/drain regions. The selective etch and deposition process is configured to selectively form a dielectric protection layer along an upper surface of the gate capping layer while concurrently selectively etching the lower ILD layer and defining the contact openings. Then, the conductive contacts are formed within the contact openings. The dielectric protection layer is configured to protect the gate capping layer while etching the lower ILD layer and forming the contact openings, such that the formation of volatile by-products, reduction of a thickness of the gate capping layer, and rounding of corners of the gate capping layer may be mitigated and/or prevented. This reduces parasitic capacitance between adjacent contacts and reduces damage to the gate capping layer, thereby increasing a performance and structural integrity of the integrated chip.

[0016] FIG. 1 illustrates a cross-sectional view of some embodiments of an integrated chip **100** having a gate capping layer **114** overlying a gate electrode **108**.

[0017] In some embodiments, the integrated chip **100** includes a transistor structure **101** disposed on/within a substrate **102**. In various embodiments, the substrate **102** may, for example, be or comprise bulk silicon, any type of semiconductor body (e.g., silicon, SiGe, etc.), a silicon-on-insulator (SOI) substrate, another suitable substrate material, and/or one or more die on a wafer, as well as any other type of semiconductor layers, epitaxial layers, or dielectric layers associated therewith. The transistor structure **101** can be a logic device that includes the gate electrode **108** separated from the substrate **102** by a gate dielectric layer **106**. A pair of source/drain regions **104** is disposed within and/or on the substrate **102** on opposite sides of the gate electrode **108**. The transistor structure **101** can be a single-gate planar transistor device as well as a multi-gate transistor device, such as a fin field-effect transistor (FinFET). Further, the transistor structure **101** can also be other devices such as gate-all-around (GAA) devices, omega-gate devices, partially-depleted SOI (PD-SOI) devices, fully-depleted SOI (FD-SOI) devices, or other applicable devices.

[0018] In various embodiments, conductive contacts are respectively coupled to the gate electrode **108**, the source/drain regions **104**, body contact regions (not shown), or other regions of the transistor structure **101**. In various embodiments, the conductive contacts are part of a middle-of-the-line (MOL) structure overlying the substrate **102** and may comprise a plurality of upper conductive contacts **120** and a plurality of lower source/drain contacts **116**. In some embodiments, each conductive contact may comprise a lower contact structure **122** surrounded by a lower inter-level dielectric (ILD) layer **117** and/or an upper contact structure **124** surrounded by an upper ILD layer **118**. The upper contact structure **124** overlies the lower contact structure **122**. For example, at least a portion of the upper conductive contacts **120** may be part of the upper contact structure **124** and the lower source/drain contacts **116** may be part of the lower contact structure **122**. In various embodiments, the upper conductive contacts **120** and the lower source/drain contacts **116** may, for example, be or comprise tungsten, copper, aluminum, ruthenium, titanium, tantalum, titanium

nitride, tantalum nitride, another conductive material, or any combination of the foregoing. Further, a lower etch stop layer **110** may be disposed along and lining sidewalls of the lower ILD layer **117**. [0019] In various embodiments, a sidewall spacer **112** is disposed alongside the gate electrode **108**. The sidewall spacer **112** extends along opposing sidewalls of the gate electrode **108** and opposing sidewalls of the gate dielectric layer **106**. Further, the sidewall spacer **112** is disposed along the lower etch stop layer **110**. In some embodiments, a top surface of the sidewall spacer **112** is disposed above a top surface of the gate electrode **108**. Further, the top surface of the sidewall spacer **112** may be aligned or coplanar with a top surface of the lower etch stop layer **110**. In further embodiments, the lower etch stop layer **110** may, for example, be or comprise silicon nitride, a low-k dielectric material, silicon, silicon carbon nitride, another suitable dielectric material, or any combination of the foregoing. In yet further embodiments, the sidewall spacer **112** may, for example, be or comprise silicon nitride, silicon carbide, silicon oxynitride, silicon oxycarbide, another suitable material, or any combination of the foregoing.

[0020] In various embodiments, the gate electrode **108** is recessed from a top surface of the lower ILD layer **117**. A gate capping layer **114** is disposed on the gate electrode **108**. A top surface of the gate capping layer **114** may be aligned or coplanar with the top surface of the lower ILD layer **117**. In further embodiments, the gate capping layer **114** may comprise a non-oxide dielectric material. For example, the gate capping layer **114** may be or comprise silicon, silicon nitride, silicon carbon nitride, a non-oxide dielectric material, another suitable dielectric material, or any combination of the foregoing. In yet further embodiments, the lower etch stop layer **110** and the gate capping layer **114** may comprise a same material (e.g., silicon nitride, silicon, silicon carbon nitride, or the like). The gate capping layer **114** continuously extends from the top surface of the lower etch stop layer **110** and the top surface of the sidewall spacer **112**, along a sidewall of the sidewall spacer **112**, to the top surface of the gate electrode **108**. In further embodiments, the gate capping layer **114** is T-shaped, such that a lower portion of the gate capping layer **114** is surrounded by the sidewall spacer **112** and an upper portion of the gate capping layer **114** directly overlies the lower etch stop layer **110** and the sidewall spacer **112**.

[0021] In some embodiments, the lower contact structure **122** comprises the plurality of lower source/drain contacts **116** that overlie each source/drain region **104**. In various embodiments, the lower source/drain contacts **116** each fill a slot between and directly contacts sidewalls of the lower etch stop layer **110** and the gate capping layer **114**. In yet further embodiments, top surfaces of the lower source/drain contacts **116** may be aligned or coplanar with the top surface of the gate capping layer **114** and/or the top surface of the lower ILD layer **117**. In further embodiments, the plurality of upper conductive contacts **120** directly overlie and are electrically coupled to the lower source/drain contacts **116** and the gate electrode **108** of the transistor structure **101**. The upper conductive contact **120** directly overlying the gate electrode **108** of the transistor structure **101** continuously extends through the upper ILD layer **118** and the gate capping layer **114** to contact the gate electrode **108**.

[0022] In various embodiments, during fabrication of the lower contact structure **122** a selective etch and deposition process is performed on the lower ILD layer **117** and the gate capping layer **114** to form openings within the lower ILD layer **117** directly over corresponding source/drain regions **104**. The selective etch and deposition process is configured to selectively form a dielectric protection layer (not shown) along the top surface of the gate capping layer **114** while concurrently selectively etching the lower ILD layer **117**. Subsequently, the lower source/drain contacts **116** are formed within the openings such that top surfaces of the lower source/drain contacts **116** are aligned or coplanar with the top surface of the gate capping layer **114**. By forming the dielectric protection layer along the top surface of the gate capping layer **114** while concurrently etching the lower ILD layer **117**, damage to the gate capping layer **114** may be mitigated or prevented. For example, formation of volatile by-products from etchants used during the selective etch and deposition process along the top surface of the gate capping layer **114** is mitigated or prevented,

thereby increasing a structural integrity and endurance of the integrated chip **100**. Further, the dielectric protection layer prevents rounding of the corners of the gate capping layer **114**, such that upper opposing sidewalls of the gate capping layer **114** meet the top surface of gate capping layer **114** at a right angle. This, in part, facilitates the lower source/drain contacts **116** each having a rectangular shape, thereby increasing a distance between adjacent lower source/drain contacts **116** and decreasing a parasitic capacitance within the lower and upper contact structures **122**, **124**. Furthermore, by preventing damage to the gate capping layer **114** while forming the lower source/drain contacts **116**, an ability for the gate capping layer **114** to mitigate or prevent damage to the gate electrode **108** during subsequent fabrication steps and/or operation of the integrated chip **100** is increased. Thus, the selective etch and deposition process increases a performance and structural integrity of the integrated chip **100**.

[0023] FIG. 2A illustrates a cross-sectional view of some embodiments of an integrated chip **200a** corresponding to some alternative embodiments of the integrated chip **100** of FIG. 1, in which the upper conductive contacts **120** comprise a liner layer **202a** and a conductive body **202b**. The liner layer **202a** laterally surrounds the conductive body **202b** and extends along a lower surface of the conductive body **202b**. In various embodiments, the liner layer **202a** may comprise or be configured as a diffusion barrier layer or an adhesive layer. Further, the liner layer **202a** may, for example, be or comprise titanium, tantalum, titanium nitride, tantalum nitride, another conductive material, or any combination of the foregoing. The conductive body **202b** may, for example, be or comprise aluminum, copper, ruthenium, tungsten, another conductive material, or any combination of the foregoing.

[0024] In some embodiments, the gate capping layer **114** comprises a first gate capping structure **114a** laterally adjacent to a second gate capping structure **114b**, where the first and second gate capping structures **114a**, **114b** directly overlie a corresponding gate electrode **108**. In various embodiments, a width  $w1$  of the first gate capping structure **114a** is about 45 nanometers (nm), within a range of about 30 to 60 nm, or another suitable value. In various embodiments, widths of each gate capping structure directly overlying a corresponding gate electrode **108** are equal to one another and may respectively be about 45 nm, within a range of about 30 to 60 nm, or another suitable value. In some embodiments, a vertical distance  $v1$  between a top surface of the source/drain regions **104** and a top surface of the gate capping layer **114** is about 120 nm, within a range of about 80 to 160 nm, or another suitable value. In further embodiments, a lateral distance  $d1$  between adjacent gate capping structures of the gate capping layer **114** is about 15 nm, within a range of about 10 to 20 nm, or another suitable value. In some embodiments, the lateral distance  $d1$  may correspond to a width of a corresponding lower source/drain contact **116** disposed between the adjacent gate capping structures of the gate capping layer **114**. For example, the lateral distance  $d1$  may be equal to the width of the lower source/drain contact **116** disposed between the first gate capping structure **114a** and the second gate capping structure **114b**.

[0025] FIG. 2B illustrates a cross-sectional view of some embodiments of an integrated chip **200b** corresponding to some alternative embodiments of the integrated chip **100** of FIG. 1, in which an upper etch stop layer **204** is disposed between the lower ILD layer **117** and the upper ILD layer **118**. The upper etch stop layer **204** may, for example, be or comprise silicon nitride, silicon carbide, silicon carbon nitride, another suitable dielectric material, or any combination of the foregoing. In some embodiments, the upper etch stop layer **204** may comprise a same material as the lower etch stop layer **110** and/or may comprise a same material as the gate capping layer **114**. Further, the plurality of upper conductive contacts **120** may comprise a body contact **206**. The body contact **206** comprises a first portion **206a** electrically coupled to one of the source/drain regions **104** via a corresponding lower source/drain contact **116** and a second portion **206b** electrically coupled to the gate electrode **108**. Thus, the body contact **206** is configured to directly electrically couple the gate electrode **108** to an adjacent source/drain region **104**.

[0026] FIG. 2C illustrates a cross-sectional view of some embodiments of an integrated chip **200c**

corresponding to some alternative embodiments of the integrated chip **100** of FIG. 1, in which a center segment **117c** of the lower ILD layer **117** is disposed directly between adjacent gate capping structures of the gate capping layer **114**.

[0027] FIG. 3A illustrates a cross-sectional view of some embodiments of an integrated chip **300a** corresponding to some alternative embodiments of the integrated chip **100** of FIG. 1, in which each lower source/drain contact **116** comprises one or more protrusions that conform to an adjacent rounded corner of the gate capping layer **114**. The one or more protrusions of the lower source/drain contacts **116** directly overlie at least a portion of the gate capping layer **114**.

[0028] In various embodiments, the plurality of lower source/drain contacts **116** includes a first lower source/drain contact **116a**. The first lower source/drain contact **116a** has a first straight sidewall **302** and a second straight sidewall **304** opposite the first straight sidewall **302**. In various embodiments, the first and second straight sidewalls **302**, **304** are substantially straight and/or are each perpendicular relative to a top surface of the substrate **102**. In some embodiments, the first lower source/drain contact **116a** comprises a body region **116br** and one or more protrusions **306**, **308** that extend from the body region **116br** to an adjacent rounded corner of the gate capping layer **114**. The body region **116br** is defined between the first straight sidewall **302** and the second straight sidewall **304**, such that a width  $W_c$  of the body region **116br** is defined between the first and second straight sidewalls **302**, **304**. In various embodiments, the width  $W_c$  is about 15 nanometers (nm), within a range of about 10 to 20 nm, or another suitable value. In yet further embodiments, the first lower source/drain contact **116a** comprises a first protrusion **306** that extends from the body region **116br** in a first direction and a second protrusion **308** that extends from the body region **116br** in a second direction that is opposite the first direction. A first width  $W_{p1}$  of the first protrusion **306** is defined from the body region **116br** to an outermost point of the first protrusion **306**, and a second width  $W_{p2}$  of the second protrusion **308** is defined from the body region **116br** to an outermost point of the second protrusion **308**. In various embodiments, the first and second widths  $W_{p1}$ ,  $W_{p2}$  are respectively about 0.75 nm, within a range of about 0.5 to 1 nm, less than about 1 nm, or another suitable value.

[0029] In addition, in some embodiments, a ratio between the first width  $W_{p1}$  and the width  $W_c$  (e.g.,  $W_{p1}:W_c$ ) is, for example, about 1:20, within a range of about 0.25:20 to 1:20, or another suitable value. In further embodiments, a ratio between the second width  $W_{p2}$  and the width  $W_c$  (e.g.,  $W_{p2}:W_c$ ) is, for example, about 1:20, within a range of about 0.25:20 to 1:20, or another suitable value. In various embodiments, if the ratios between the first and second width  $W_{p1}$ ,  $W_{p2}$  and the width  $W_c$  (e.g.,  $W_{p1}:W_c$  and  $W_{p2}:W_c$ ) are relatively low (e.g., less than about 1:20), then a distance between the lower source/drain contacts **116** and laterally adjacent upper conductive contacts **120** is increased. This, in part, reduces parasitic capacitance within the lower and upper contact structures **122**, **124**, thereby increasing a performance of the integrated chip **300a**. Thus, in some embodiments, the width  $W_c$  of the body region **116br** is about 20, 30, 40, or within a range of about 20 to 60 times greater than the first and second widths  $W_{p1}$ ,  $W_{p2}$ . In yet further embodiments, if the ratios between the first and second width  $W_{p1}$ ,  $W_{p2}$  and the width  $W_c$  are relatively high (e.g., greater than about 1:20), then a distance between the lower source/drain contacts **116** and laterally adjacent upper contacts **120** is decreased. This may increase parasitic capacitance within the lower and upper contact structures **122**, **124**, thereby degrading a performance of the integrated chip **300a**. It will be appreciated that the aforementioned ratios described with reference to the integrated chip **300a** of FIG. 3A are also applicable to the structures of FIGS. 3B, 17, and 22B.

[0030] FIG. 3B illustrates a cross-sectional view of some embodiments of an integrated chip **300b** corresponding to some alternative embodiments of the integrated chip **200c** of FIG. 2C, in which upper corners of the gate capping layer **114** that are directly adjacent to a corresponding lower source/drain contact **116** are curved or rounded. In further embodiments, upper corners of the gate capping layer **114** that contact the lower ILD layer **117** are not curved or rounded and conform to a

rectangular shape.

[0031] FIG. 4 illustrates a perspective view of an integrated chip **400** having a gate capping layer **114** overlying a gate electrode **108**.

[0032] In some embodiments, the integrated chip **400** comprises FinFET devices, nanowire devices, or other gate-all-around (GAA) devices. The substrate **102** may comprise a lower base portion and a plurality of upper columns raised from the lower base portion, extended along a channel length direction, and arranged in parallel from one another. Epitaxial semiconductor layers may be disposed on the plurality of upper columns of the substrate **102** and may comprise high doped portions on opposite sides as the source/drain regions **104** and lightly doped or non-doped portions between the source/drain regions **104** as channel regions. A conductive layer may be disposed on the channel regions as the gate electrode **108** and separated from the channel regions by a gate dielectric (e.g., the gate dielectric layer **106**) and configured to control current flow of the channel regions. The gate electrode **108** may extend along a channel width direction perpendicular to the channel length direction. The gate electrode **108** may extend to wrap around sidewalls of the channel regions. As discussed in the figures above, in some embodiments, the gate capping layer **114** is disposed on the gate electrode **108**, where the lower source/drain contacts **116** are disposed along sidewalls of the gate capping layer **114**. The gate capping layer **114** may have a top surface aligned or coplanar with that of the lower source/drain contacts **116**. In further embodiments, the plurality of upper conductive contacts **120** extend through the upper ILD layer **118** and the upper etch stop layer **204** to contact an underlying lower source/drain contact **116** and/or an underlying gate electrode **108**.

[0033] FIGS. 5-14 illustrate cross-sectional views **500-1400** of some embodiments of a method of forming an integrated chip having a gate capping layer over a gate electrode according to the present disclosure. Although the cross-sectional views **500-1400** shown in FIGS. 5-14 are described with reference to a method, it will be appreciated that the structures shown in FIGS. 5-14 are not limited to the method but rather may stand alone separate of the method. Although FIGS. 5-14 are described as a series of acts, it will be appreciated that these acts are not limiting in that the order of the acts can be altered in other embodiments, and the methods disclosed are also applicable to other structures. In other embodiments, some acts that are illustrated and/or described may be omitted in whole or in part.

[0034] As shown in the cross-sectional views **500** and **600** of FIGS. 5 and 6, transistor structures **101** are prepared over a substrate **102** and surrounded by a lower ILD layer **117**. The transistor structures **101** each have a gate dielectric layer **106** over the substrate **102**, a gate electrode **108** over the gate dielectric layer **106**, and a pair of source/drain regions **104** disposed within or on the substrate **102** on opposite sides of the gate electrode **108** (e.g., see FIG. 6). The gate electrode **108** may, for example, be or comprise polysilicon, aluminum, titanium, tungsten, another suitable conductive material, or any combination of the foregoing. Further, the gate dielectric layer **106** may, for example, be or comprise silicon dioxide, a high-k dielectric material, another suitable dielectric material, or any combination of the foregoing.

[0035] In some embodiments, each transistor structure **101** may be formed by a replacement gate process. For example, as shown in the cross-sectional view **500** of FIG. 5, dummy gate structures **502** are firstly formed and patterned over the substrate **102**. Further, a sidewall spacer **112** is formed alongside the dummy gate structures **502** lining or covering sidewalls of the dummy gate structures **502**. In various embodiments, the sidewall spacer **112** comprises silicon dioxide, silicon nitride, silicon carbide, aluminum oxide, aluminum nitride, another suitable dielectric material, or any combination of the foregoing. In some embodiments, the sidewall spacer **112** may comprise multiple layers, such as main spacer walls, liner layers, and the like. In further embodiments, a process for forming the sidewall spacer **112** may include: depositing (e.g., by chemical vapor deposition (CVD), physical vapor deposition (PVD), atomic layer deposition, etc.) a dielectric material over the dummy gate structures **502** and the substrate **102**; and performing an etching



process on the dielectric material such that a top surface of the sidewall spacer **112** is substantially aligned or coplanar with top surfaces of the dummy gate structures **502**.

[0036] In various embodiments, the source/drain regions **104** may each be a doped region disposed within the substrate **102**. In such embodiments, a process for forming the source/drain regions **104** may include performing an ion implantation process according to a masking layer (e.g., the dummy gate structures **502** and/or the sidewall spacer **112** may function as a masking layer during the ion implantation process) to implant dopants within the substrate **102**, thereby forming the source/drain regions **104**. In further embodiments, the source/drain regions **104** may each be or comprise an epitaxial semiconductor material disposed on and/or within the substrate **102**. In such embodiments, the source/drain regions **104** may be formed by epitaxially growing silicon germanium or some other suitable semiconductor material over/on the substrate **102**. For example, the source/drain regions **104** may be formed by molecular beam epitaxy (M BE), vapor phase epitaxy (V PE), liquid phase epitaxy (LPE), some other epitaxial process, or any combination of the foregoing. In some alternative embodiments, the source/drain regions **104** may be deposited rather than grown and the deposition may, for example, comprise a CVD process, a PVD process, and ALD process, or some other suitable deposition process. In some embodiments, the source/drain regions **104** may be doped (e.g., by an ion implantation process) such that the source/drain regions **104** comprise doped silicon germanium or some other suitable doped semiconductor material.

[0037] As shown in the cross-sectional view **500** of FIG. **5**, a lower etch stop layer **110** is formed lining upper surfaces of the substrate **102** and extending upwardly along the sidewall spacer **112**. Further, a dielectric layer is deposited (e.g., by CVD, PVD, ALD etc.) over the transistor structures **101** and the lower etch stop layer **110** followed by a planarization process (e.g., a chemical mechanical planarization (CM P)) to form the lower ILD layer **117**. The lower etch stop layer **110** may be formed by a deposition process such as a CVD process, a PVD process, an ALD process, or another suitable growth or deposition process. Further, the lower ILD layer **117** may be deposited by a plasma enhanced CVD (PECVD) process, a PVD process, an ALD process, or another suitable growth or deposition process. The lower etch stop layer **110** and the lower ILD layer **117** may be planarized by a CM P process such that a top surface of the lower etch stop layer **110** is aligned or coplanar with a top surface of the lower ILD layer **117**. In various embodiments, the lower ILD layer **117** may, for example, be or comprise silicon dioxide, doped silicon dioxide, oxygen-doped silicon carbide, silicon oxycarbide, a low-k dielectric material, another dielectric, or any combination of the foregoing. Further, the lower etch stop layer **110** may, for example, be or comprise a low-k dielectric material, silicon nitride, another dielectric material, or any combination of the foregoing.

[0038] In further embodiments, for the replacement gate process, the dummy gate structures **502** in FIG. **5** may be removed and replaced by the gate electrode **108** made of metal or another conductive material (e.g., polysilicon). Further, the gate dielectric layer **106** may also be formed after removing the dummy gate structures **502**. To form the gate electrode **108**, stacks of metal materials may be filled in gate openings followed by a planarization process to remove excessive portions above the lower ILD layer **117**. In some embodiments, the stacks of metal materials may comprise or be made of titanium nitride, tantalum nitride, titanium aluminum, aluminum, tungsten, another suitable metal material, or any combination of the foregoing.

[0039] As shown in the cross-sectional view **700** of FIG. **7**, the gate electrode **108** is patterned such that a top surface of the gate electrode **108** is recessed below the top surface of the lower ILD layer **117**. In some embodiments, a process for patterning the gate electrode **108** includes: forming a masking layer **702** over the lower ILD layer **117**, thereby leaving the gate electrode **108** exposed; and performing an etching process according to the masking layer **702** to lower the top surface of the gate electrode **108** to a position lower than the top surface of the lower IL D layer **117**. In further embodiments, the etching process comprises an anisotropic etch such as a vertical dry etch, and the recessed top surface of the gate electrode **108** is substantially planar as shown in FIG. **7**. In

yet further embodiments, the etching process comprises an isotropic etch such as a wet etch, and the recessed top surface of the gate electrode **108** can have a concave shape (not shown). In various embodiments, a removal process is performed to remove the masking layer **702** (not shown).

[0040] As shown in the cross-sectional view **800** of FIG. **8**, a gate capping layer **114** is formed on the recessed gate electrode **108**. In various embodiments, the gate capping layer **114** is configured to protect the gate electrode **108** during subsequent processing steps and may be referred to as a protection layer. In some embodiments, the gate capping layer **114** may be formed by a deposition process such as a CVD process, a PVD process, an ALD process, or another suitable growth or deposition process. In further embodiments, a planarization process (e.g., a CMP process) is performed on the gate capping layer **114** such that a top surface of the gate capping layer is aligned or coplanar with the top surface of the lower ILD layer **117**. In various embodiments, the gate capping layer **114** may be or comprise silicon, silicon nitride, silicon carbon nitride, another suitable dielectric material, or any combination of the foregoing. In further embodiments, the gate capping layer **114** may be or comprise a non-oxide dielectric material.

[0041] As shown in the cross-sectional view **900** of FIG. **9**, an upper dielectric structure **908** is formed over the lower ILD layer **117** and the gate capping layer **114**. In various embodiments, the upper dielectric structure **908** may be formed by depositing the upper dielectric structure **908** over the lower ILD layer **117** by a CVD process, a PVD process, an ALD process, or another suitable growth or deposition process. Further, after depositing the upper dielectric structure **908** over the lower ILD layer **117**, a planarization process (e.g., a CMP process) may be performed on the upper dielectric structure **908** such that a top surface of the upper dielectric structure **908** is substantially flat. Further, a masking structure **902** is formed over the upper dielectric structure **908** where the masking structure **902** comprises a hard masking layer **904** disposed along the upper dielectric structure **908** and a dielectric layer **906** overlying the hard masking layer **904**. In various embodiments, both the upper dielectric structure **908** and the lower ILD layer **117** comprise an oxide (e.g., silicon dioxide) different than a material of the gate capping layer **114**. For example, the gate capping layer **114** comprises a non-oxide material.

[0042] As shown in the cross-sectional view **1000** of FIG. **10**, a selective etch and deposition process is performed on the upper dielectric structure **908**, the gate capping layer **114**, and the lower ILD layer **117**, thereby forming source/drain contact openings **1004** over the source/drain regions **104** and selectively forming a dielectric protection layer **1002** along the top surface of the gate capping layer **114**. In various embodiments, the selective etch and deposition process is configured to selectively form the dielectric protection layer **1002** along the gate capping layer **114** while concurrently etching the upper dielectric structure **908**, the lower ILD layer **117**, and/or the lower etch stop layer **110** to form the source/drain contact openings **1004**. In various embodiments, the dielectric protection layer **1002** may, for example, be or comprise tungsten, boron nitride, molybdenum, another suitable material, or any combination of the foregoing. In further embodiments, the selective etch and deposition process may include performing a selective plasma etch process on the upper dielectric structure **908**, the lower ILD layer **117**, and/or the etch stop layer **110** while concurrently performing a selective CVD process to selectively form the dielectric protection layer **1002** along the upper surface of the gate capping layer **114**.

[0043] In various embodiments, the selective etch and deposition process may be carried out in a processing chamber (not shown), where the substrate **102** is disposed within the processing chamber. In further embodiments, the selective etch and deposition process may include performing a selective etch process with a plasma etchant while concurrently performing a selective deposition process (e.g., a selective CVD process). For example, the selective etch and deposition process can be carried out by concurrently flowing the plasma etchant and a selective precursor gas within the processing chamber, where the plasma etchant is configured to selectively etch the lower ILD layer **117** and/or the etch stop layer **110** and the selective precursor gas is configured to selectively form the dielectric protection layer **1002** along the upper surface of the

gate capping layer **114**. In various embodiments, the plasma etchant may be formed as an inductively coupled plasma (ICP), a capacitively coupled plasma (CCP), an electron cyclotron resonance (ECR) plasma, or the like by a plasma source.

[0044] In some embodiments, the selective etch and deposition process is conducted within the processing chamber at a temperature of about 100° Celsius, in a range of between about 0° Celsius and 150° Celsius, or another suitable value, and at a pressure in a range of between about 1 millitorr and 1 torr, or another suitable value. In various embodiments, the plasma etchant is formed by the plasma source at a power in a range of about 300 watts and 1,200 watts, a range of about 50 watts and 2,000 watts, or another suitable value. In yet further embodiments, a bias voltage is applied to a wafer chuck (not shown) configured to hold the substrate **102** within the processing chamber. The bias voltage may, for example, be greater than 0 volts, in a range of between about 0 volts and 500 volts, or another suitable value. A carrier gas in the processing chamber may consist of hydrogen (H.sub.2), nitrogen (N.sub.2), and/or oxygen (O.sub.2). In some embodiments, the selective etch and deposition process is carried out by concurrently flowing the plasma etchant and the selective precursor gas within the processing chamber. For example, the plasma etchant may be flowed into the processing chamber by a first gas line and the selective precursor gas may be flowed into the processing chamber by a second gas line that is separate from the first gas line. In some embodiments, by flowing the plasma etchant and the selective precursor gas into the processing chamber via separate gas lines, defect issues may be mitigated and/or prevented because the plasma etchant and the selective precursor gas do not interact with one another in a single gas line. In yet further embodiments, a flow rate of the plasma etchant into the processing chamber is greater than a flow rate of the selective precursor gas into the processing chamber. In some embodiments, the plasma etchant may be flowed into the processing chamber at a first flow rate between about 10 standard cubic centimeter per minute (sccm) and about 200 sccm, or another suitable value. In further embodiments, the selective precursor gas may be flowed into the processing chamber at a second flow rate between about 10 sccm and about 100 sccm, or another suitable value. In yet further embodiments, the carrier gas may be flowed into the processing chamber at a flow rate between about 100 sccm and about 1,000 sccm, or another suitable value.

[0045] In various embodiments, the plasma etchant may be or comprise fluorocarbon (e.g., CF.sub.4), carbon hydrogen fluoride (e.g., CHF.sub.3, CH.sub.2F.sub.2, CH.sub.3F), sulfur hexafluoride (e.g., SF.sub.6), chlorine (e.g., Cl.sub.2), boron trichloride (e.g., BCl.sub.3), hydrogen bromide (e.g., HBr), nitrogen trifluoride (e.g., NF.sub.3), another suitable etchant, or any combination of the foregoing. In further embodiments, the selective precursor gas may be or comprise a metal fluoride (e.g., tungsten hexafluoride (WF.sub.6)), boron chloride (e.g., BCl.sub.3), dimethyl, trimethyl, another suitable precursor, or any combination. In various embodiments, the selective precursor gas is flowed into the processing chamber with the carrier gas (e.g., hydrogen (H.sub.2) or nitrogen (N.sub.2)). In an embodiment, if the selective precursor gas comprises tungsten hexafluoride (e.g., WF.sub.6) then the carrier gas may consist essentially of hydrogen (H.sub.2), and if the selective precursor gas comprises boron chloride (e.g., BCl.sub.3) then the carrier gas may consist essentially of nitrogen (N.sub.2). In some embodiments, by virtue of the selective precursor gas being flowed into the processing chamber, the dielectric protection layer **1002** is selectively formed along the upper surface of the gate capping layer **114** while not forming on the lower ILD layer **117**. This, in part, occurs because the gate capping layer **114** comprises a non-oxide dielectric material while the lower ILD layer **117** comprises an oxide. Thus, the selective etch and deposition process is configured to selectively form the dielectric protection layer **1002** along a non-oxide dielectric material. Further, during the selective etch and deposition process, the dielectric protection layer **1002** is selectively formed along the gate capping layer **114** more quickly than it is removed and/or etched by the plasma etchant. Thus, the dielectric protection layer **1002** may act as a hard mask layer during the selective etch and deposition process that

prevents or mitigates the gate capping layer **114** from being etched and/or damaged by the plasma etchant. This mitigates the formation of volatile by-products from the gate capping layer **114** and the plasma etchant, mitigates a reduction of a thickness of the gate capping layer **114**, and mitigates the rounding of corners of the gate capping layer **114**, thereby increasing a performance and structural integrity of the transistor structures **101**.

[0046] In yet further embodiments, the lower etch stop layer **110** may be etched more quickly than the upper dielectric structure **908** and/or the lower ILD layer **117** during the selective etch and deposition process. In further embodiments, after forming the source/drain contact openings **1004**, a removal process may be performed to selectively remove the dielectric protection layer **1002** from over the gate capping layer **114** (not shown). In various embodiments, the removal process may include performing a wet etch process and/or a dry etch process. For example, the removal process may include exposing the dielectric protection layer **1002** to deionized water, ammonia water, hydrogen peroxide, another suitable chemical, or any combination of the foregoing. In yet further embodiments, the removal process may further include exposing the dielectric protection layer **1002** to a fluorine-base etchant, or another suitable etchant.

[0047] As shown in the cross-sectional view **1100** of FIG. **11**, a conductive structure **1102** is formed within the source/drain contact openings (**1004** of FIG. **10**) and over the source/drain regions **104**. In various embodiments, the conductive structure **1102** may, for example, be or comprise tungsten, copper, ruthenium, aluminum, molybdenum, tantalum, titanium, another conductive material, or any combination of the foregoing. In further embodiments, before forming the conductive structure **1102**, a glue and/or barrier layer (not shown) may be formed over the substrate **102** that help to bond and/or prevent diffusion. In further embodiments, the conductive structure **1102** may be formed over the substrate **102** by depositing the conductive structure **1102** on the source/drain regions **104** and the gate capping layer **114** by a CVD process, a PVD process, a sputtering process, an electroplating process, or another suitable deposition or growth process. In further embodiments, a metallization process may be performed prior to forming the conductive structure **1102** to form a semiconductor-metal compound film or layer (such as silicide, germanides, germanosilicide, etc.) at an interface of the conductive structure **1102** and the exposed portion of the upper surface of the source/drain regions **104**, thereby providing a low resistance contact (not shown).

[0048] As shown in the cross-sectional view **1200** of FIG. **12**, a planarization process is performed on the structure of FIG. **11**, thereby defining a plurality of lower source/drain contacts **116**. In various embodiments, forming the plurality of lower source/drain contacts **116** may include the acts illustrated and/or described in FIGS. **9-12**. In some embodiments, the planarization process may include a CMP process, an etching process, another suitable planarization process, or any combination of the foregoing. In further embodiments, the planarization process is performed in such a manner that the top surface of the gate capping layer **114** is aligned or coplanar with top surfaces of the lower source/drain contacts **116**.

[0049] As shown in the cross-sectional view **1300** of FIG. **13**, an upper ILD layer **118** is formed over the gate capping layer **114** and the plurality of lower source/drain contacts **116**. In various embodiments, the upper ILD layer **118** may be or comprise tetraethylorthosilicate (TEOS) oxide, un-doped silicate glass, silicon dioxide, doped silicon dioxide such as borophosphosilicate glass (BPSG), fused silica glass (FSG), phosphosilicate glass (PSG), boron doped silicon glass (BSG), another suitable dielectric material, or any combination of the foregoing. In yet further embodiments, the upper ILD layer **118** may comprise a same material as the lower ILD layer **117**. In some embodiments, the upper ILD layer **118** may be deposited by a CVD process, a PECVD process, a PVD process, an ALD process, or another suitable deposition or growth process.

[0050] As shown in the cross-sectional view **1400** of FIG. **14**, a plurality of upper conductive contacts **120** is formed within the upper ILD layer **118** and over the plurality of lower source/drain contacts **116**. In various embodiments, a process for forming the plurality of upper conductive contacts **120** may include: forming a masking layer (not shown) over the upper ILD layer **118**;

patterning the upper ILD layer **118** and/or the gate capping layer **114** according to the masking layer to define a plurality of contact openings (not shown); depositing (e.g., by CVD, PVD, sputtering, electroplating, etc.) a conductive material (e.g., aluminum, copper, tungsten, ruthenium, titanium nitride, tantalum nitride, another conductive material, or any combination of the foregoing) over the substrate **102** and filling the plurality of contact openings; and performing a planarization process (e.g., a CMP process) into the conductive material until an upper surface of the upper ILD layer **118** is reached. In such embodiments, patterning the upper ILD layer **118** and/or the gate capping layer **114** may include performing a wet etch process, a dry etch process, another suitable etch process, or any combination of the foregoing. By performing the selective etch and deposition process of FIG. **10** to define the source/drain contact openings (**1004** of FIG. **10**) for the lower source/drain contacts **116**, damage to the gate capping layer **114** is mitigated, thereby mitigating and/or preventing damage to the gate electrode **108** during formation of the upper conductive contacts **120** and/or during subsequent processing steps.

[0051] FIGS. **15-17** illustrate cross-sectional views **1500-1700** of some embodiments of a second method for forming an integrated chip having a gate capping layer over a gate electrode according to the present disclosure. For example, FIGS. **15-17** illustrate alternative embodiments of acts that may be performed in place of the acts at FIGS. **10-12** of the method of FIGS. **5-14**. Thus, in some embodiments, the second method includes a method that alternatively proceeds from FIGS. **5-9** to FIGS. **15-17**, and from FIG. **17** to FIGS. **13-14** (i.e., skipping FIGS. **10-12**).

[0052] As shown in the cross-sectional view **1500** of FIG. **15**, a selective etch and deposition process is performed on the upper dielectric structure **908**, the gate capping layer **114**, and the lower ILD layer **117**, thereby forming source/drain contact openings **1004** over the source/drain regions **104** and selectively forming the dielectric protection layer **1002** along the top surface of the gate capping layer **114**. In various embodiments, the selective etch and deposition process may be performed as described with reference to FIG. **10** above. However, in some embodiments, the selective etch and deposition process may reduce a thickness of the gate capping layer **114** and/or round the corners of the gate capping layer **114**. This, in part, may occur because a first flow rate of the plasma etchant may be substantially greater than a second flow rate of the selective precursor gas during the selective etch and deposition process. For example, the first flow rate of the plasma etchant may be between about 30 sccm and about 50 sccm, and the second flow rate of the selective precursor gas may be about 20 sccm. For ease of illustration, an upper portion of the gate capping layer **114** is represented by a dashed-line, and in some embodiments, the upper portion of the gate capping layer **114** may be removed by the selective etch and deposition process. After the removal of the upper portion of the gate capping layer **114**, the dielectric protection layer **1002** is selectively formed along the exposed upper surface of the gate capping layer **114** such that the dielectric protection layer **1002** conforms to the exposed upper surface of the gate capping layer **114**.

[0053] In various embodiments, a first gate capping structure **114a** of the gate capping layer **114** has its thickness reduced by a first vertical loss value **1502** of about 1 nanometer (nm), within a range of about 0.1 to 2 nm, less than about 2 nm, or another suitable value. In further embodiments, a second gate capping structure **114b** of the gate capping layer **114** has its thickness reduced by a second vertical loss value **1504** of about 1 nm, within a range of about 0.1 to 2 nm, less than about 2 nm, or another suitable value. In some embodiments, the first vertical loss value **1502** is equal to the second vertical loss value **1504**. In yet further embodiments, a width **w1** of the second gate capping structure **114b** of the gate capping layer **114** is about 45 nm, within a range of about 30 to 60 nm, or another suitable value. In various embodiments, a lateral distance **d1** between adjacent structures of the gate capping layer **114** is about 15 nm, within a range of about 10 to 20 nm, or another suitable value. Further, a height of each outer corner of the exposed regions of the gate capping layer **114** may be reduced by a vertical distance **1506** during the selective etch and deposition process. In some embodiments, the vertical distance **1506** may be about 2.5 nm, within a

range of about 0.1 to 5 nm, less than 5 nm, or another suitable value. In yet further embodiments, after performing the selective etch and deposition process, a removal process is performed to remove the dielectric protection layer **1002** from over the gate capping layer **114** (not shown). [0054] As shown in the cross-sectional view **1600** of FIG. **16**, a conductive structure **1102** is formed within the source/drain contact openings (**1004** of FIG. **10**) and over the source/drain regions **104**. In some embodiments, before forming the conductive structure **1102**, a glue and/or barrier layer (not shown) may be formed over the substrate **102** that help to bond and/or prevent diffusion. In further embodiments, the conductive structure **1102** may be formed over the substrate **102** by depositing the conductive structure **1102** on the source/drain regions **104** and the gate capping layer **114** by a CVD process, a PVD process, a sputtering process, an electroplating process, or another suitable deposition or growth process. In yet further embodiments, a metallization process may be performed prior to forming the conductive structure **1102** to form a semiconductor-metal compound film or layer (such as silicide) at an interface of the conductive structure **1102** and the exposed portion of the upper surface of the source/drain regions **104**, thereby providing a low resistance contact (not shown). Further, the conductive structure **1102** is formed such that it conforms to the rounded corners of the gate capping layer **114**.

[0055] As shown in the cross-sectional view **1700** of FIG. **17**, a planarization process is performed on the structure of FIG. **16**, thereby defining a plurality of lower source/drain contacts **116**. In various embodiments, FIGS. **15-17** illustrate an alternative embodiment of forming the plurality of lower source/drain contacts **116**. In some embodiments, the planarization process may include a CMP process, an etching process, another suitable planarization process, or any combination of the foregoing. In yet further embodiments, due to the conductive structure (**1102** of FIG. **16**) conforming to the rounded corners of the gate capping layer **114**, at least a portion of each lower source/drain contact **116** comprise an outer protrusion that directly overlies and conforms to a shape of an adjacent segment of the gate capping layer **114**.

[0056] FIGS. **18-22A** illustrate cross-sectional views **1800-2200a** of some embodiments of a third method for forming an integrated chip having a gate capping layer over a gate electrode according to the present disclosure. For example, FIGS. **18-22A** illustrate alternative embodiments of acts that may be performed in place of the acts at FIGS. **9-14** of the method of FIGS. **5-14**. Thus, in some embodiments, the third method includes a method that alternatively proceeds from FIGS. **5-8** to FIGS. **18-22A** (i.e., skipping FIGS. **9-14**).

[0057] As shown in the cross-sectional view **1800** of FIG. **18**, an upper dielectric structure **1808** is formed over the lower ILD layer **117** and the gate capping layer **114**. In various embodiments, the upper dielectric structure **1808** may be formed by depositing the upper dielectric structure **1808** over the lower ILD layer **117** by a CVD process, a PVD process, an ALD process, or another suitable growth or deposition process. Further, a masking structure **1802** is formed over the upper dielectric structure **1808** where the masking structure **1802** comprises a hard masking layer **1804** disposed along the upper dielectric structure **1808** and a dielectric layer **1806** overlying the hard masking layer **1804**.

[0058] As shown in the cross-sectional view **1900** of FIG. **19**, a patterning process is performed on the upper dielectric structure **1808** according to the masking structure **1802**, thereby defining a plurality of openings **1902** within the upper dielectric structure **1808**. In various embodiments, the patterning process includes performing a dry etch process, a wet etch process, another suitable etch process, or any combination of the foregoing.

[0059] As shown in the cross-sectional view **2000** of FIG. **20**, a selective etch and deposition process is performed on the upper dielectric structure **1808**, the gate capping layer **114**, and the lower ILD layer **117**, thereby forming source/drain contact openings **1004** over the source/drain regions **104** and selectively forming a dielectric protection layer **1002** along the top surface of the gate capping layer **114**. In various embodiments, the selective etch and deposition process is performed as illustrated and/or described in FIG. **10**. In further embodiments, the selective etch and

deposition process expands the openings (**1902** of FIG. **19**) while forming the source/drain contact openings **1004** and exposes a top surface of the source/drain regions **104**. In various embodiments, after performing the selective etch and deposition process a removal process is performed to remove the dielectric protection layer **1002** from along the top surface of the gate capping layer **114** (not shown).

[0060] As shown in the cross-sectional view **2100** of FIG. **21**, a plurality of lower source/drain contacts **116** is formed within the source/drain contact openings (**1004** of FIG. **20**) over corresponding source/drain regions **104**. In various embodiments, a process for forming the plurality of lower source/drain contacts **116** includes: depositing (e.g., by a CVD process, a PVD process, a sputtering process, an electroplating process, etc.) a conductive structure (not shown) over the substrate **102** such that the conductive structure fills the source/drain contact openings (**1004** of FIG. **20**); and performing a planarization process (e.g., a CMP process) into the conductive structure until a top surface of the gate capping layer **114** is reached. In various embodiments, the lower source/drain contacts **116** are formed such that top surfaces of the lower source/drain contacts **116** are aligned or coplanar with the top surface of the gate capping layer **114** and/or the top surface of the lower ILD layer **117**. In yet further embodiments, the planarization process may remove the upper dielectric structure (**1808** of FIG. **20**) and/or the masking structure (**1802** of FIG. **20**).

[0061] As shown in the cross-sectional view **2200a** of FIG. **22A**, an upper ILD layer **118** is formed over the lower ILD layer **117** and a plurality of upper conductive contacts **120** is formed within the upper ILD layer **118**. In various embodiments, the upper ILD layer **118** may be formed as illustrated and/or described in FIG. **13**. In further embodiments, the plurality of upper conductive contacts **120** may be formed as illustrated and/or described in FIG. **13**.

[0062] FIG. **22B** illustrates a cross-sectional view **2200b** of some alternative embodiments of the cross-sectional view **2200a** of FIG. **22A**, in which the plurality of lower source/drain contacts **116** is formed over corresponding source/drain regions **104** such that each lower source/drain contact **116** comprises one or more protrusions that conforms to an adjacent rounded corner of the gate capping layer **114**. In such embodiments, the selective etch and deposition process utilized to form the source/drain contact openings (e.g., **1004** of FIG. **20**) may be performed as illustrated and/or described in FIG. **15**.

[0063] In various embodiments, the plurality of lower source/drain contacts **116** includes a first lower source/drain contact **116a**. The first lower source/drain contact **116a** has a first straight sidewall **302** and a second straight sidewall **304** opposite the first straight sidewall **302**. In some embodiments, the first lower source/drain contact **116a** comprises a body region **116br** and one or more protrusions **306**, **308** that extend from the body region **116br** to an adjacent rounded corner of the gate capping layer **114**. The body region **116br** is defined between the first straight sidewall **302** and the second straight sidewall **304**, such that a width  $W_c$  of the body region **116br** is defined between the first and second straight sidewalls **302**, **304**. In various embodiments, the width  $W_c$  is about 15 nm, within a range of about 10 to 20 nm, or another suitable value. In yet further embodiments, the first lower source/drain contact **116a** comprises a first protrusion **306** that extends from the body region **116br** in a first direction and a second protrusion **308** that extends from the body region **116br** in a second direction that is opposite the first direction. A first width  $W_{p1}$  of the first protrusion **306** is defined from the body region **116br** to an outermost point of the first protrusion **306**, and a second width  $W_{p2}$  of the second protrusion **308** is defined from the body region **116br** to an outermost point of the second protrusion **308**. In various embodiments, the first and second widths  $W_{p1}$ ,  $W_{p2}$  are respectively about 0.75 nm, within a range of about 0.5 to 1 nm, less than about 1 nm, or another suitable value.

[0064] In some embodiments, a ratio between the first width  $W_{p1}$  and the width  $W_c$  (e.g.,  $W_{p1}:W_c$ ) is, for example, about 1:20, within a range of about 0.25:20 to 1:20, or another suitable value. In further embodiments, a ratio between the second width  $W_{p2}$  and the width  $W_c$  (e.g.,

Wp2:Wc) is, for example, about 1:20, within a range of about 0.25:20 to 1:20, or another suitable value. In various embodiments, if the ratios between the first and second width Wp1, Wp2 and the width Wc (e.g., Wp1:Wc and Wp2:Wc) are relatively low (e.g., less than about 1:20), then a distance between the lower source/drain contacts **116** and laterally adjacent upper conductive contacts **120** is increased. This, in part, reduces parasitic capacitance between the lower source/drain contacts **116** and the upper conductive contacts **120**. In yet further embodiments, if the ratios between the first and second width Wp1, Wp2 and the width Wc are relatively high (e.g., greater than about 1:20), then a distance between the lower source/drain contacts **116** and laterally adjacent upper contacts **120** is decreased. This may increase parasitic capacitance between the lower source/drain contacts **116** and the upper conductive contacts **120**.

[0065] FIG. **23** illustrates a method **2300** of forming an integrated chip having a gate capping layer over a gate electrode according to the present disclosure. Although the method **2300** is illustrated and/or described as a series of acts or events, it will be appreciated that the method is not limited to the illustrated ordering or acts. Thus, in some embodiments, the acts may be carried out in different orders than illustrated, and/or may be carried out concurrently. Further, in some embodiments, the illustrated acts or events may be subdivided into multiple acts or events, which may be carried out at separate times or concurrently with other acts or sub-acts. In some embodiments, some illustrated acts or events may be omitted, and other un-illustrated acts or events may be included.

[0066] At act **2302**, a transistor structure is formed having a pair of source/drain regions and a gate electrode between the source/drain regions. FIGS. **5** and **6** illustrate cross-sectional views **500** and **600** corresponding to some embodiments of act **2302**.

[0067] At act **2304**, a lower inter-level dielectric (ILD) layer is formed over the pair of source/drain regions and around the gate electrode. FIG. **6** illustrates the cross-sectional view **600** corresponding to some embodiments of act **2304**.

[0068] At act **2306**, a gate capping layer is formed over the gate electrode. FIGS. **7** and **8** illustrate cross-sectional views **700** and **800** corresponding to some embodiments of act **2306**.

[0069] At act **2308**, a selective etch and deposition process is performed to form a dielectric protection layer on the gate capping layer while etching the lower ILD layer to form a plurality of source/drain contact openings within the lower ILD layer. FIG. **10** illustrates the cross-sectional view **1000** corresponding to some embodiments of act **2308**. FIG. **15** illustrates the cross-sectional view **1500** corresponding to some alternative embodiments of act **2308**. FIG. **20** illustrates the cross-sectional view **2000** corresponding to yet another alternative embodiment of act **2308**.

[0070] At act **2310**, a plurality of lower source/drain contacts is formed within the source/drain contact openings and over the source/drain regions. FIGS. **11** and **12** illustrate cross-sectional views **1100** and **1200** corresponding to some embodiments of act **2310**. FIGS. **16** and **17** illustrate cross-sectional views **1600** and **1700** corresponding to some alternative embodiments of act **2310**. FIG. **21** illustrates the cross-sectional view **2100** corresponding to yet another alternative embodiment of act **2310**.

[0071] At act **2312**, an upper ILD layer is formed over the plurality of lower source/drain contacts and the lower ILD layer. FIG. **13** illustrates the cross-sectional view **1300** corresponding to some embodiments of act **2312**.

[0072] At act **2314**, a plurality of upper conductive contacts is formed within the upper IL D layer and over the gate electrode and the lower source/drain contacts. FIG. **14** illustrates the cross-sectional view **1400** corresponding to some embodiments of act **2314**. FIG. **22A** illustrates the cross-sectional view **2200a** corresponding to some other embodiments of act **2314**. FIG. **22B** illustrates the cross-sectional view **2200b** corresponding to some alternative embodiments of act **2314**.

[0073] Accordingly, in some embodiments, the present application relates to a method for forming an integrated chip (and a corresponding structure) that includes performing a selective etch and deposition process on a gate capping layer and a lower ILD layer to selectively form a dielectric



protection layer on the gate capping layer while concurrently etching the lower ILD layer to form contact openings over corresponding source/drain regions. Subsequently, lower source/drain contacts are formed within the contact openings and over the source/drain regions.

[0074] In some embodiments, the present application provides a method for manufacturing an integrated chip, including: forming a transistor structure over a substrate, wherein the transistor structure comprises a pair of source/drain regions and a gate electrode between the source/drain regions; forming a lower inter-level dielectric (ILD) layer over the pair of source/drain regions and around the gate electrode; forming a gate capping layer over the gate electrode; and performing a selective etch and deposition process to form a dielectric protection layer on the gate capping layer while forming a contact opening within the lower ILD layer; and forming a lower source/drain contact within the contact opening.

[0075] In some embodiments, the present application provides a method for manufacturing an integrated chip, including: forming a transistor structure over a substrate, wherein the transistor structure comprises a pair of source/drain regions and a gate electrode between the source/drain regions; forming a lower etch stop layer and a lower inter-level dielectric (ILD) layer over the pair of source/drain regions and surrounding the gate electrode over the substrate, wherein the lower ILD layer comprises a first dielectric material; recessing the gate electrode such that a top surface of the gate electrode is below a top surface of the lower etch stop layer; forming a gate capping layer on the recessed gate electrode such that a top surface of the gate capping layer is aligned with a top surface of the lower ILD layer, wherein the gate capping layer comprises a second dielectric material different from the first dielectric material; performing a selective etch and deposition process to selectively form a dielectric protection layer along the top surface of the gate capping layer while concurrently selectively etching the lower ILD layer to define contact openings over the source/drain regions, wherein the selective etch and deposition process comprises concurrently flowing a plasma etchant at a first flow rate and a selective precursor gas at a second flow rate less than the first flow rate over the substrate; performing a removal process to remove the dielectric protection layer; and forming lower source/drain contacts within the contact openings.

[0076] In some embodiments, the present application provides an integrated chip, including a transistor structure disposed over a substrate and including a pair of source/drain regions and a gate electrode between the pair of source/drain regions; a lower inter-layer dielectric (ILD) layer disposed over the pair of source/drain regions and surrounding the gate electrode, wherein a top surface of the gate electrode is recessed from a top surface of the lower ILD layer, wherein the lower ILD layer comprises a first dielectric material; and a gate capping layer disposed on the gate electrode, wherein the gate capping layer has a top surface aligned with the top surface the lower ILD layer, wherein the gate capping layer comprises a second dielectric material different from the first dielectric material; and a lower source/drain contact disposed over a first source/drain region of the pair of source/drain regions, wherein a top surface of the lower source/drain contact is aligned with the top surface of the gate capping layer, wherein the lower source/drain contact comprises a body region and a first protrusion, wherein the first protrusion extends laterally from the body region to a point over a portion the gate capping layer, wherein a width of the body region is at least 20 times greater than a width of the first protrusion.

[0077] The foregoing outlines features of several embodiments so that those skilled in the art may better understand the aspects of the present disclosure. Those skilled in the art should appreciate that they may readily use the present disclosure as a basis for designing or modifying other processes and structures for carrying out the same purposes and/or achieving the same advantages of the embodiments introduced herein. Those skilled in the art should also realize that such equivalent constructions do not depart from the spirit and scope of the present disclosure, and that they may make various changes, substitutions, and alterations herein without departing from the spirit and scope of the present disclosure.

## Claims

1. An integrated chip, comprising: a gate structure over a substrate; a pair of source/drain structures on opposing sides of the gate structure; a dielectric layer over the substrate and around the gate structure, wherein the dielectric layer comprises a first material; an etch stop layer adjacent to opposing sidewalls of the gate structure; a capping layer on the gate structure, wherein the capping layer comprises a first segment and a second segment under the first segment, wherein the first segment contacts the etch stop layer and the second segment contacts the gate structure, wherein the capping layer comprises a second material different from the first material; and a conductive structure over a first source/drain structure in the pair of source/drain structures, wherein the conductive structure contacts the capping layer and the etch stop layer.
2. The integrated chip of claim 1, wherein the first material is an oxide and the second material is a non-oxide.
3. The integrated chip of claim 1, wherein the etch stop layer comprises the second material.
4. The integrated chip of claim 1, further comprising: a sidewall spacer between the etch stop layer and the gate structure, wherein a top surface of the sidewall spacer is aligned with a top surface of the etch stop layer.
5. The integrated chip of claim 4, wherein an outer sidewall of the second segment is aligned with a first sidewall of the opposing sidewalls of the gate structure, wherein the sidewall spacer contacts the outer sidewall of the second segment and the first sidewall.
6. The integrated chip of claim 1, wherein opposing sidewalls of the first segment are aligned with opposing sidewalls of the etch stop layer, wherein a first lateral distance between the opposing sidewalls of the first segment is greater than a second lateral distance between opposing sidewalls of the second segment.
7. The integrated chip of claim 6, wherein a height of the first segment is less than a height of the second segment.
8. The integrated chip of claim 1, wherein the conductive structure comprises a curved surface contacting the capping layer.
9. An integrated chip, comprising: a first source/drain structure laterally adjacent to a gate structure; a capping layer over the gate structure, wherein a width of the capping layer is greater than a width of the gate structure; and a conductive structure over the first source/drain structure, wherein an upper surface of the conductive structure is aligned with an upper surface of the capping layer, and wherein the conductive structure comprises a lateral segment that overlies an outer region of the capping layer.
10. The integrated chip of claim 9, wherein the lateral segment contacts a curved surface of the capping layer.
11. The integrated chip of claim 9, wherein the capping layer comprises a first segment over a second segment, wherein a width of the first segment is greater than a width of the second segment, wherein a height of the first segment is greater than a height of the lateral segment.
12. The integrated chip of claim 11, wherein the first segment comprises a sidewall segment under the lateral segment, wherein a height of the sidewall segment is less than the height of the lateral segment.
13. The integrated chip of claim 11, wherein an outer sidewall of the gate structure faces the lateral segment, wherein a distance between the outer sidewall of the gate structure and the lateral segment is less than a height of the second segment.
14. The integrated chip of claim 9, further comprising: a sidewall spacer between the conductive structure and the gate structure; and an etch stop layer between the conductive structure and the sidewall spacer, wherein a lateral thickness of the etch stop layer along a sidewall of the conductive structure is less than a length of the lateral segment.
15. The integrated chip of claim 14, wherein an outer point of the lateral segment directly overlies

an upper surface of the sidewall spacer.

**16.** The integrated chip of claim 9, further comprising: a first conductive interconnect over the conductive structure; and a second conductive interconnect extending through the capping layer to contact the gate structure.

**17.** An integrated chip, comprising: a gate structure arranged between a pair of source/drain structures; a spacer layer on opposing sidewalls of the gate structure; an etch stop layer on opposing sidewalls of the spacer layer, wherein a top surface of the gate structure is arranged below a top surface of the etch stop layer; a capping layer over the gate structure, wherein the capping layer extends from the top surface of the etch stop layer to the top surface of the gate structure; and a conductive structure over a first source/drain structure in the pair of source/drain structures, wherein the conductive structure contacts the capping layer and the etch stop layer, wherein a top surface of the conductive structure is aligned with a top surface of the capping layer.

**18.** The integrated chip of claim 17, wherein a first vertical distance between the top surface of the gate structure and the top surface of the etch stop layer is greater than a second vertical distance between the top surface of the etch stop layer and the top surface of the capping layer.

**19.** The integrated chip of claim 17, wherein in cross-sectional view the capping layer is T-shaped.

**20.** The integrated chip of claim 17, further comprising: an inter-layer dielectric (ILD) layer around the gate structure, wherein a top surface of the ILD layer is aligned with the top surface of the capping layer, and wherein the ILD layer comprises an oxide and the capping layer comprises a non-oxide.

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